

(Use several sheets if necessary)

PJW153

Application Number

Applicant(s)

Brun La Fontaine, Jongwook Kye, Harry Levinson

Filing Date

Group Art Unit

unknown

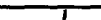
U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	A	NEW PHASE SHIFT GRATINGS FOR MEASURING ABERRATIONS, by Hiroshi Nomura, published by SPIE, dated February 27, 2001 (11 pages)

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Drawline through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.